

lib.

T.E. (EXTC) V (R)
 Elements of Microelectronics
 (REVISED COURSE)

01/06/09
 3-6 p.m.
 VR-5160

(3 Hours)

[Total Marks : 100]

N.B. : (1) Question No. 1 is **compulsory**.

(2) Attempt any **four** questions out of remaining **six** questions.

1. (a) Give merits and demerits of MOS Integrated Circuits. 5
 (b) Define LSI, MSI, VLSI and ULSI Circuits. 5
 (c) Discuss fabrication density, system speed, power dissipation and their inter-dependence in detail. 5
 (d) Explain MOSFET operation. 5
2. (a) What are the various crystal growth techniques used in silicon industries ? Explain any one in brief. 10
 (b) With neat diagram explain the fabrication sequence of CMOS Inverter using N-well process. 10
3. (a) Describe the formation of resistors in integrated circuit. How will you optimize the design ? 10
 (b) What are different types of scaling ? Explain their advantages and disadvantages. 10
4. (a) What is the minimum number of isolation regions required to realize in monolithic form for 2 input. TTL NAND Gate. Draw monolithic layout of this gate ? 10
 (b) Explain different short channel effects in MOSFET. 10
5. (a) Explain the need of design rules and explain significance of λ based design rules. 10
 (b) Calculate the threshold voltage V_{TO} for a polysilicon gate n-channel MOS transistor, with the following parameters : 10
 Substrate doping density $N_A = 10^{16} \text{ cm}^{-3}$, polysilicon gate doping density $N_D = 2 \times 10^{20} \text{ cm}^{-3}$, gate oxide thickness $t_{ox} = 500 \text{ \AA}$, and oxide - interface fixed charge density $N_{ox} = 4 \times 10^{10} \text{ cm}^{-2}$.
 (Data $\frac{kT}{q} = 26 \text{ mV}$, $\epsilon_0 = 8.85 \times 10^{-14} \text{ F/cm}$, $K_{ox} = 3.9$, $n_i = 1.45 \times 10^{10} \text{ cm}^{-3}$, $k_{si} = 11.7$)
6. (a) Design CMOS logic gates for the following function. 10
 (i) $Z = \overline{(A + B) (C + D)}$
 (ii) $Z = \overline{A (B + C) + CD}$
 (b) Discuss different parasitic effects in MOS transistors. 10
7. Write short notes on the following :— 20
 (a) Butting and Buried contacts
 (b) CMOS Latchup
 (c) BJT Fabrication
 (d) IC Cross Overs.